



PATENT ABSTRACTS OF JAPAN

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(21) Application number: **06271936**(22) Date of filing: **29.09.1994**(71) Applicant: **SATO YOICHI**(72) Inventor: **SATO YOICHI****(54) MICROMACHINE WITH METALLIC ANODIZED FILM****(57) Abstract:**

PURPOSE: To provide a micromachine wherein an insulator obtained by anodizing metal is used for a structure body.

CONSTITUTION: A structure body and a moving part are constituted on a substrate such as a semiconductor by using an insulator obtained by anodizing metal as a material. The selection figure is one example wherein a substrate 1, a supporting part partially connected and a beam 2 connected thereto exist. The beam is separated from a substrate and bends and vi-

brates by an external pressure, a voltage applied to an electrode 3 in the selection figure. The above is one example, and various fine machinery devices can be acquired by combination of an insulator obtained by anodizing metal and making a resin material a sacrificial layer.

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